

Electronic Supplementary Material (ESI) for CrystEngComm.

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Liquid-phase Atomic Layer Deposition of Crystalline Hematite Without Post-growth Annealing

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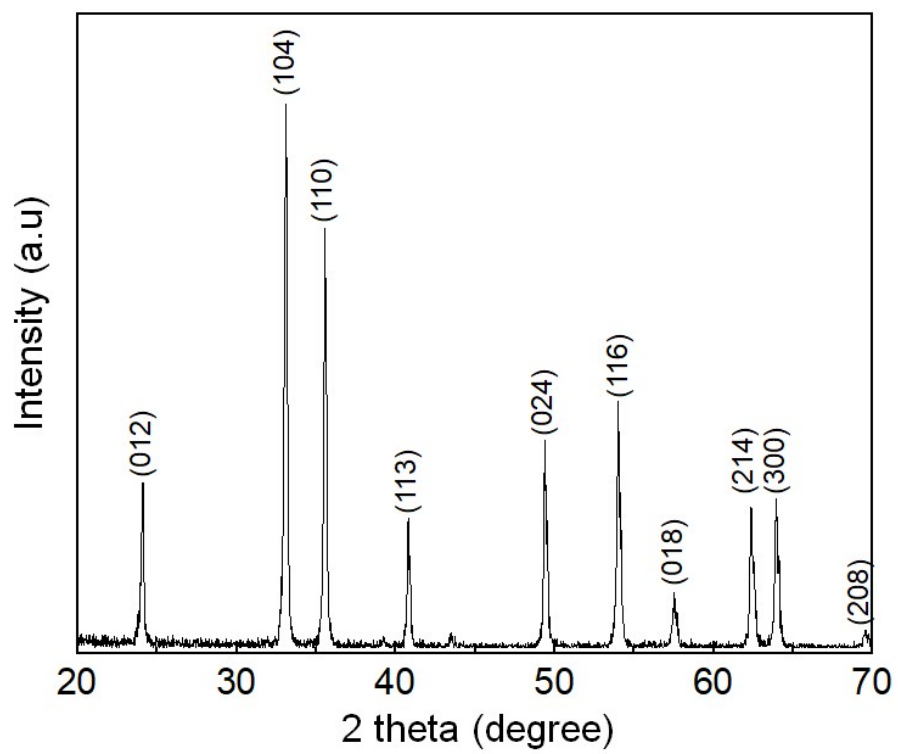
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Figure

XRD pattern of α -Fe₂O₃ powder.

S1.

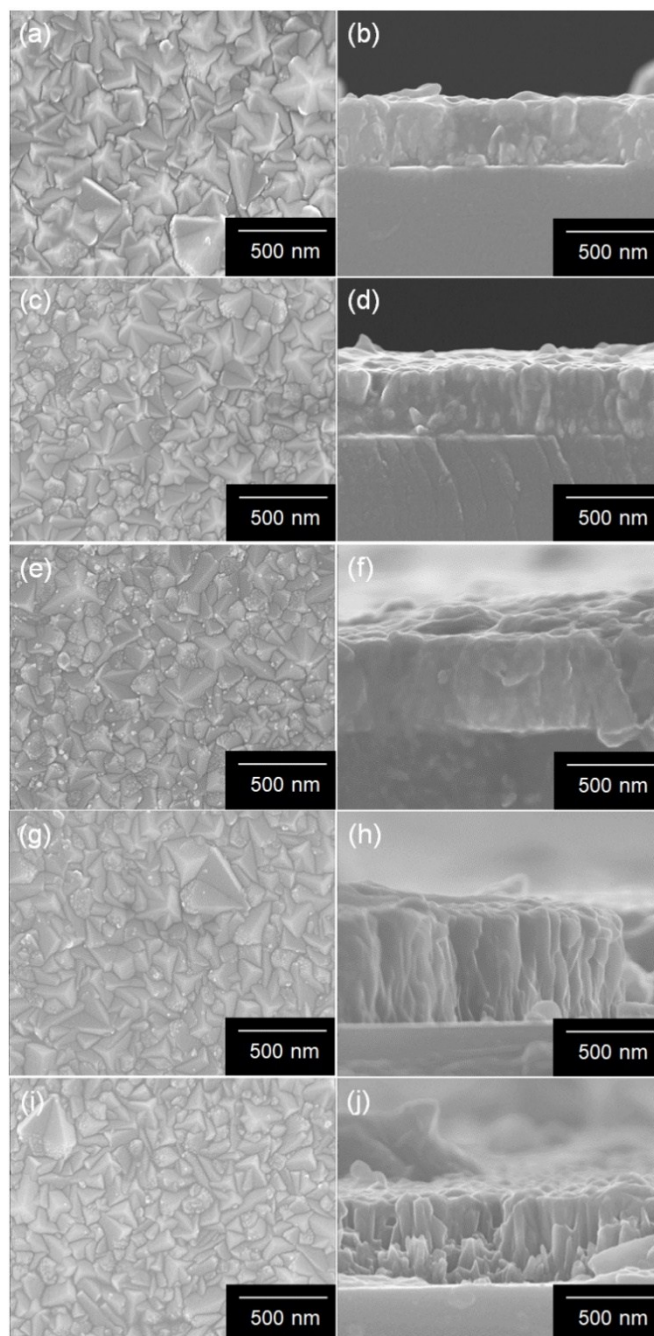


Figure S2. Surface and cross-sectional SEM images of the films fabricated with 10 mM ((a) and (b)), 20 mM ((c) and (d)), and 23 mM ((e) and (f)), 26 mM ((g) and (h)), 27 mM ((i) and (j)) of NaNO_2 . The reaction duration for the deposition of these films was 90 min.